

A facile route for the preparation of nanoparticles of the spin-crossover complex $[\text{Fe}(\text{Htrz})_2(\text{trz})](\text{BF}_4)$ in xerogel transparent composite films

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Electronic Supplementary Information

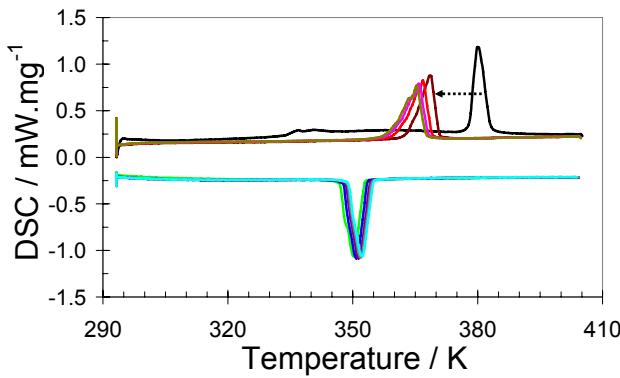


Fig. S1. DSC measurements of the bulk starting $[\text{Fe}(\text{Htrz})_2(\text{trz})](\text{BF}_4)$ **1b**.
10 Arrow shows the shift of the position of the peak after repetitive heating-
cooling cycles of temperature

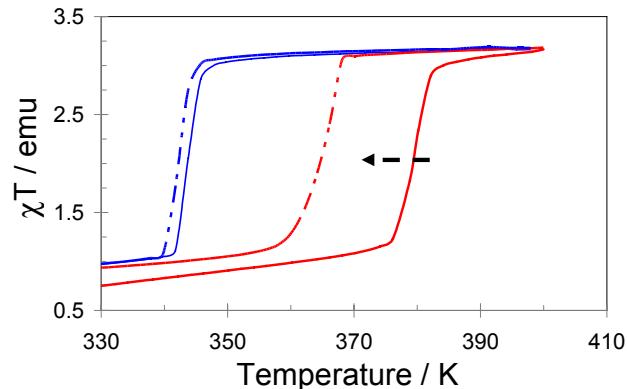


Fig. S3. χT as a function of the temperature for the bulk starting
25 $[\text{Fe}(\text{Htrz})_2(\text{trz})](\text{BF}_4)$ **1b**. Arrow shows the decrease of the hysteresis
loops width after one heating-cooling cycle of temperature

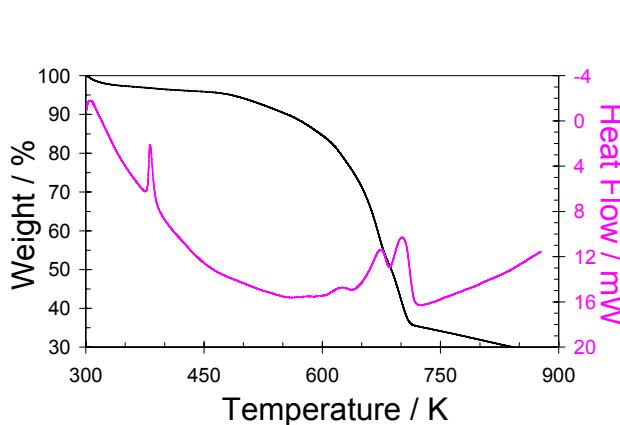


Fig. S2. TGA-TDA measurements for the bulk starting
30 $[\text{Fe}(\text{Htrz})_2(\text{trz})](\text{BF}_4)$ **1b**

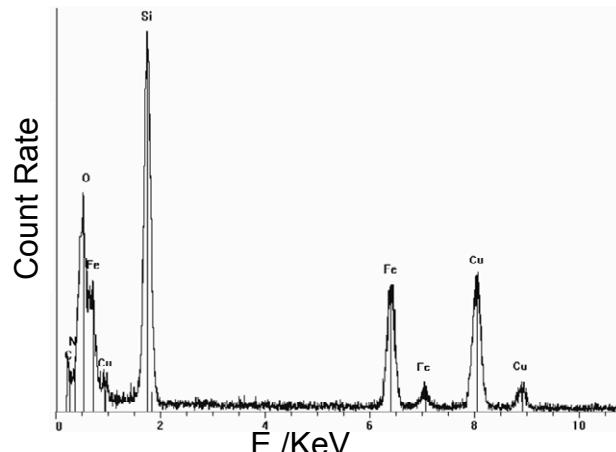


Fig. S4. EDX of an assembly of particles of **1b**@ SiO_2 (in TMOS)
observed by high resolution microscopy.

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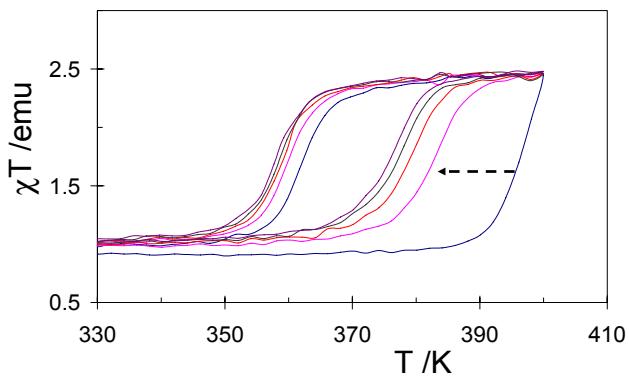


Fig. S5. χT as a function of the temperature for the films of **1b@SiO₂** (in TMOS). Arrow shows the decrease of the hysteresis loops width after repetitive heating-cooling cycles of temperature

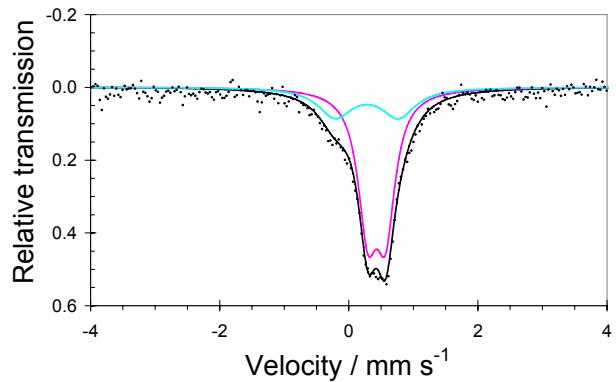


Fig. S8. Mössbauer spectra of **1b@SiO₂** (in TMOS) at 293 K

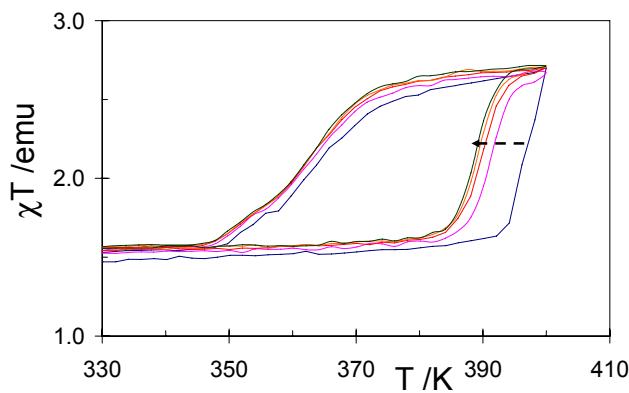


Fig. S6. χT as a function of the temperature for the monoliths of **1b@SiO₂** (in TMOS). Arrow shows the decrease of the hysteresis loop width after repetitive one heating-cooling cycle of temperature

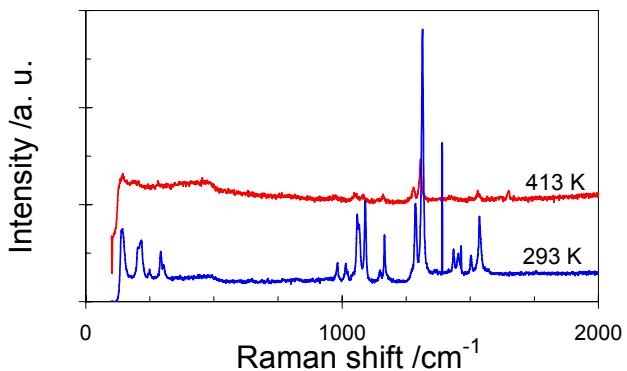


Fig. S9. Raman spectrum of films of **1b@SiO₂** in TEOS at 293 and 413 K between 100 and 2000 cm^{-1}

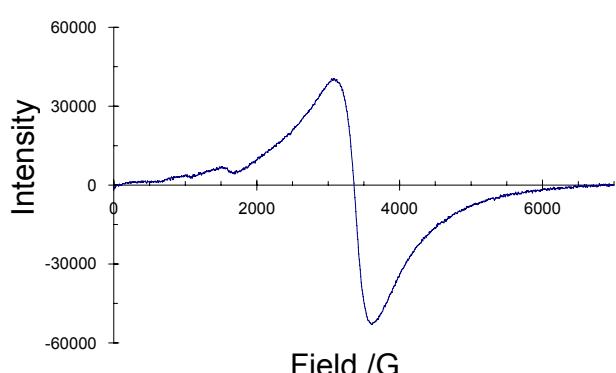


Fig. S7. EPR spectrum of **1b@SiO₂** (in TMOS) at 293 K.

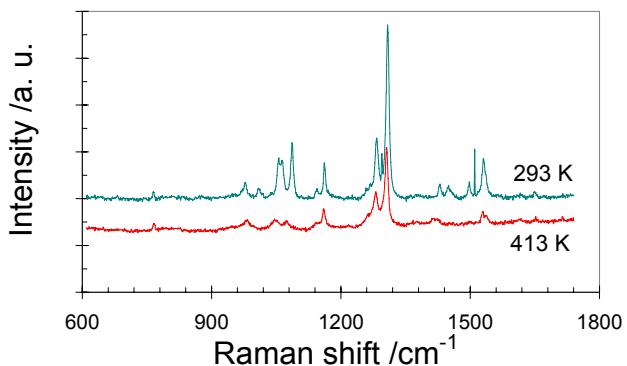


Fig. S10. Raman spectrum of films of **1b@SiO₂** in TMOS at 293 and 413 K between 600 and 1700 cm^{-1}

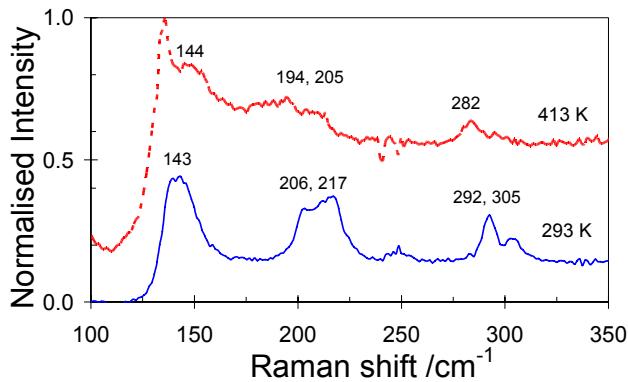


Fig. S11. Raman spectrum of films of **1b**@SiO₂ in TEOS at 293 and 413 K between 100 and 350 cm⁻¹

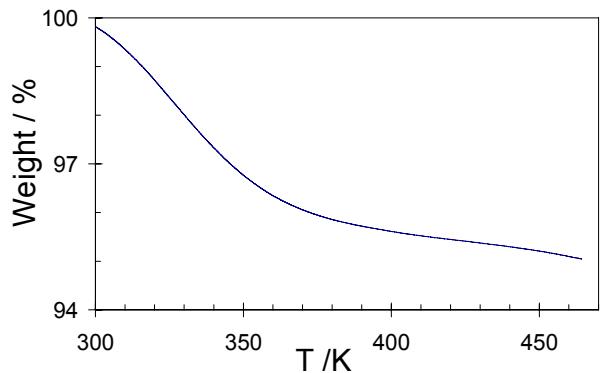
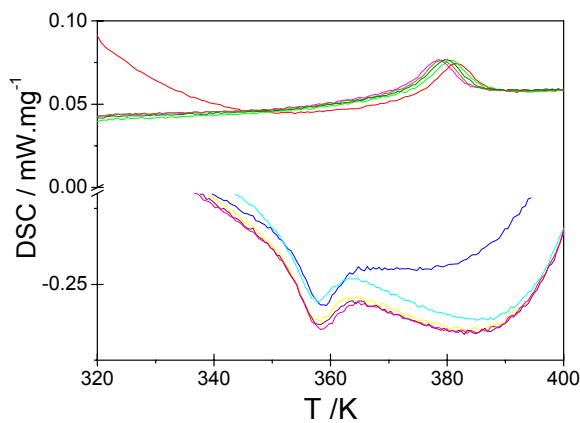
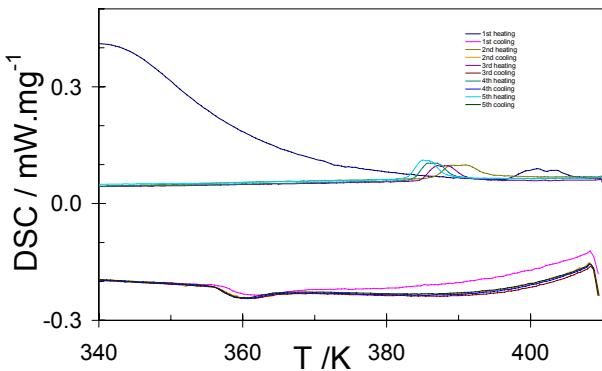


Fig. S14. TGA of film of **1b**@SiO₂ in TMOS



5 Fig. S12. DSC measurements of films of **1b**@SiO₂ in TMOS with repetitive heating-cooling cycles of temperature



10 Fig. S13. DSC measurements of films of **1b**@SiO₂ in TEOS with repetitive heating-cooling cycles of temperature